

**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q87267

Masahiko HATA

Appln. No.: 10/530,562

Group Art Unit: 1792

Confirmation No.: 8996

Examiner: Felisa Carla HITESHEW

Filed: April 7, 2005

For: METHOD FOR PRODUCING THIN FILM CRYSTAL WAFER, SEMICONDUCTOR  
DEVICE USING THE SAME AND METHOD FOR PRODUCING THE  
SEMICONDUCTOR DEVICE

**RESPONSE UNDER 37 C.F.R. § 1.111**

**MAIL STOP AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated January 26, 2009, please consider the remarks as  
submitted herewith on the accompanying pages.

**TABLE OF CONTENTS**

REMARKS .....	2
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